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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 8121
Kazuyuki NITTA et al. : Docket No. 2001-1143A
Serial No. 09/928,430 : Group Art Unit 1752
Filed August 14, 2001 : Examiner S. Lee

POSITIVE-WORKING PHOTORESIST
COMPOSITION AND RESIST
PATTERNING METHOD USING SAME

RESPONSE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the Official Action dated May 5, 2003, the period for response having been extended for one month by the attached Petition.